

**PATENT APPLICATION**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of

Docket No: Q85281

Yuji EGUCHI, et al.

Appln. No.: 10/518,013

Group Art Unit: 1792

Confirmation No.: 1952

Examiner: Binh X. Tran

Filed: December 14, 2004

For: OXIDE FILM FORMING METHOD AND OXIDE FILM FORMING APPARATUS

**AMENDMENT UNDER 37 C.F.R. § 1.111**

**MAIL STOP AMENDMENT**

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated December 22, 2008, please amend the above-identified application as follows on the accompanying pages. The Amendment is being filed concurrently with a Petition for Extension of Time for three months, thereby extending the date of response from March 22, 2009 to June 22, 2009. Therefore, the response is timely filed.

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